

# ENEE 691 Homework 3.v0

Spring 2023

Please submit your homework as a zip file which should include a pdf file explaining your solutions and your codes/notebook. **Due date: 9:00 PM, March 31, 2023.**

## Introduction

For this question, you will be working on a reflectance dataset. Figure shows a typical reflectance measurement setup. The one on the left measures reflectance from a p-polarized laser, the one on right from an s-polarized laser.<sup>1</sup> The wavelength of the laser is 400 nm. We place a 0.7 nm thick film on a substrate whose complex refractive index is  $\tilde{n} = n + ik$ , where the real part  $n$  is the refractive index and indicates the phase velocity, while the imaginary part  $k$  is called the optical extinction coefficient or absorption coefficient. We work either with SiO<sub>2</sub>-coated silicon substrates or glass substrates. We change the incidence angle ( $\theta_{\text{inc}}$ ) from 0 degrees to 60 degrees at a step of 1 degrees and we record the intensity of the reflected light with the help of a photodiode.

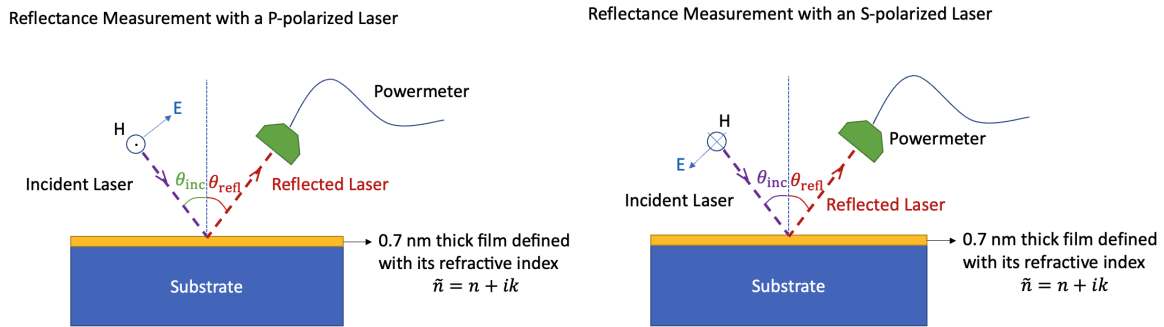


Figure 1: Reflectance measurement setup for (left) p-polarized and (right) s-polarized light.

Please the three datasets (csv) files from <https://github.com/simsekergun/ENEE691/tree/main/homework3> or use the cell below to get a copy of them in your jupyter notebook.

“Reflectance\_X\_train.csv” has 244 columns as follows.

- (a) Columns 1-61: reflectance data as a function of incidence angle (from 0 degrees to 60 degrees) of p-polarized 400 nm laser from a material with a thickness of 0.7 nm placed on top of a SiO<sub>2</sub>/silicon substrate,
- (b) Columns 62-122: similar to (a) for s-polarized laser,
- (c) Columns 123-183: similar to (a) for a glass substrate,
- (d) Columns 184-244: similar to (c) for s-polarized laser.

Each row corresponds to a unique  $(n, k)$ -pair given in “Reflectance\_Y\_train.csv”. As you can see,  $n$  changes between 0.1 and 6 and  $k$  changes between 0 and 5, both at the steps of 0.1.

Your task is finding the  $(n, k)$  values for the reflectance data given in Reflectance\_X\_test.csv, which is in the same form as the Reflectance\_X\_train.csv.

<sup>1</sup>These letters have a German origin: s = senkrecht = perpendicular, p = parallel. It basically tells whether the electric field is perpendicular or parallel to the plane of incidence.

**TASK-1 (30 points)**

Use linear regression and predict the complex refractive index, in other words  $n$  and  $k$  values for the unknown material. The reflectance from this unknown material is the "Reflectance\_X\_test.csv".

**TASK-2 (40 points)**

Note that we have 60 unique values of  $n$  and 51 unique values of  $k$ . Hence this problem (finding  $n$  and  $k$  values) can be done with multinomial logistic regression as well. You need to treat each unique value of  $n$  (first, then of  $k$ ) as a class.

**2.1** Build a multinomial logistic regression model to predict the most probable four  $n$ -values this unknown material that might have. Create a table something like this

Then use the following formula to get your final prediction for  $n_f$

Table 1: The most probable four  $n$  values predicted with the logistic regression and their probabilities.

Guess No.	Prediction $n$ value	Probability
1	$n_1$	$p_1$
2	$n_2$	$p_2$
3	$n_3$	$p_3$
4	$n_4$	$p_4$

$$n_f = \frac{\sum_{i=1}^4 n_i p_i}{\sum_{i=1}^4 p_i} \quad (1)$$

Use linear regression and predict the complex refractive index, in other words  $n$  and  $k$  values for the unknown material. The reflectance from this unknown material is the "Reflectance\_X\_test.csv".

**2.2** Repeat task **2.1** to estimate the  $k$ .

**2.3** Compare the  $n$  and  $k$  values you determined at the end of Task 1 and 2.

**TASK-3 (40 points)**

**TASK-3.1** Use SVMs to predict  $n$  and  $k$ . Since I haven't done this step by myself, I have no clue what kind of kernel we should use. Try different approaches and come up with your best solution.

**TASK-3.2** Compare the performances of regression via classification done with logistic regression vs. SVMs.